

# Systematic Design of Layered Structures for Wideband and High Frequency SAW Resonators

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## 1. Introduction

Recently, use of very thin LiNbO<sub>3</sub> (LN) and LiTaO<sub>3</sub> plates is paid much attention for realization of extremely high performance surface and bulk acoustic wave (SAW/BAW) devices.

For example, the low-cut LN plate bonded with a high velocity substrate such as SiC and sapphire have been studied extensively for realization of wideband SAW filters in the SHF range[1][2]. However, investigation was carried out for specific structures, and thus it is unclear which kind of structures are preferable for realization of wideband and high-frequency SAW resonators.

This paper discusses systematic design of layered structures for wideband and high frequency SAW Resonators.

## 2. Simulation

**Fig. 1** shows the unit cell of a one-port SAW resonator employing the IDT/piezoelectric-plate/base-substrate structure used for the analysis. For the piezoelectric-plate, 15°YX-LN[3] is chosen.

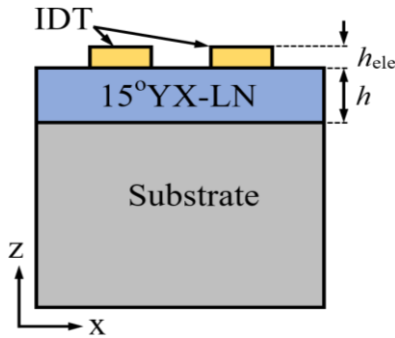


Fig. 1 The model structure used for simulation

Fig. 2 shows variation of the phase velocity  $V_p$  and the electromechanical coupling factor  $K^2$  of shear horizontal (SH) SAW with the LN thickness  $h$ . In this calculation, Al is chosen as the IDT material and its thickness  $h_{ele}$  is set at  $0.125p_1$ , where  $p_1$  is the IDT period. As the base substrate, single crystal diamond, SiC and sapphire are examined.

Large  $K^2$  is achievable only when  $h$  is large, and  $K^2$  is small where  $V_p$  is large. This trade-off relation between  $K^2$  and  $V_p$  seems to be independent of choice of the base substrate material.

Discontinuous change of  $V_p$  is seen at  $h \sim 0.4p_1$ .

This is due to coupling of the SH SAW with Rayleigh SAW, and it can be avoided by proper choice of the LN rotation angle.

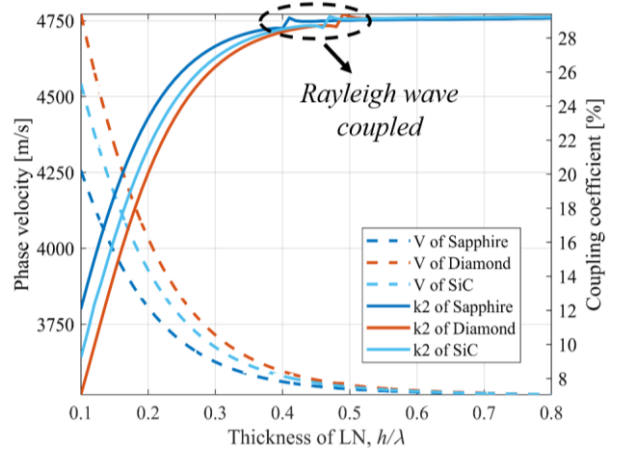


Fig. 2 Variation of phase velocity  $V_p$  and electro-mechanical coupling factor  $K^2$  with LN thickness  $h$ .

Fig. 3 shows replot of these data as  $K^2$  variation with  $V_p$ . The curve shape is almost independent of the choice of the base-substrate, and the difference becomes significant only in the region when  $K^2$  is small.

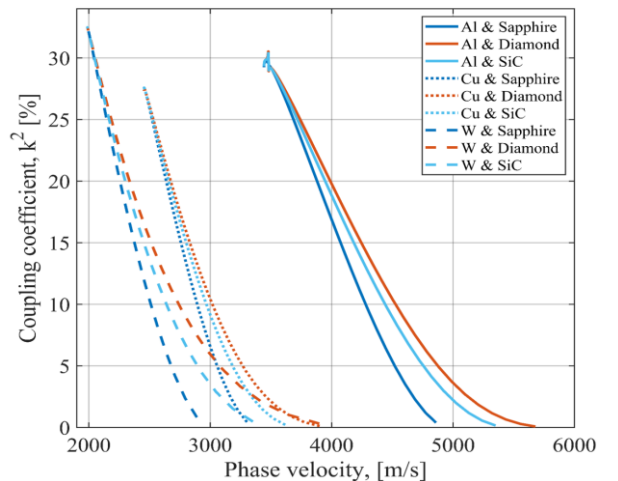


Fig. 3 Variation of the  $K^2$  and  $V_p$  relationship with choice of the base IDT materials when the LN thickness  $h$  is scanned from  $0.01p_1$  to  $p_1$ .

Fig. 3 also shows variation of  $K^2$  with  $V_p$  when either Cu or W is used for the IDT. In this calculation,  $h_{ele}$  is  $0.125p_1$ . Choice of heavy electrodes only reduces  $V_p$ , and achievable  $K^2$

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seems not to change so much. Thus we can conclude light electrode materials such as Al are preferable for this application.

Fig. 4 shows variation of  $K^2$  with  $V_p$  when  $h$  is fixed at  $0.2p_1$ , and  $h_{ele}$  is scanned from  $0.001p_1$  to  $0.5p_1$ . Giving small  $h_{ele}$  gives slight increase in  $K^2$  and slight decrease in  $V_p$ . This dependence can be explained by energy concentration to the top surface by the mass loading[4].

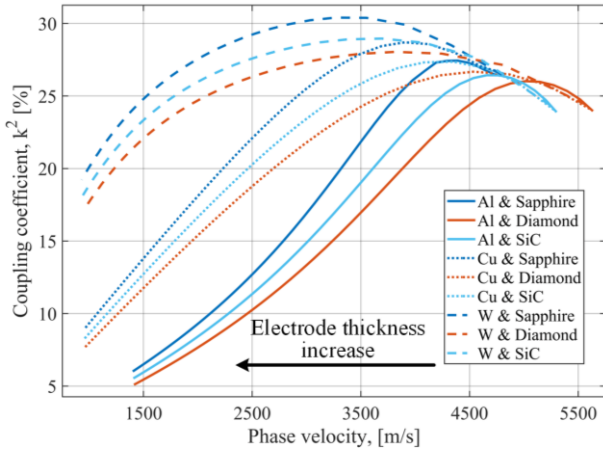


Fig. 4 Influence of the electrode thickness to the  $K^2$  and  $V_p$  relationship when  $h_{ele}$  is scanned from  $0.001p_1$  to  $0.5p_1$ .

Fig. 5 shows input admittance of infinitely long IDT on Al-IDT/ $15^\circ$ YX-LN/sapphire structure when  $h$  and  $h_{ele}$  are chosen  $0.2p_1$  and  $0.13p_1$ , respectively. Relative frequency is determined by  $f^*p_1 \cdot 1e-3$ . Large  $k^2$  of 24.0% is achieved but  $V_p$  is dropped to 3,669 m/s.

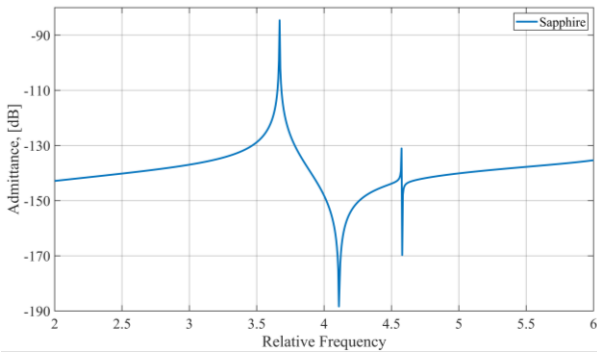


Fig. 5 Input admittance of infinitely long IDT on  $15^\circ$ YX-LN/sapphire structure.

Fig. 6 shows input admittance of infinitely long IDT on Al-IDT/ $15^\circ$ YX-LN/SiC structure when  $h$  and  $h_{ele}$  are chosen  $0.2p_1$  and  $0.1p_1$ , respectively. Relative frequency is determined by  $f^*p_1 \cdot 1e-3$ . Large  $K^2$  of 25.3% and large  $V_p$  of 4,185 m/s are attained simultaneously.

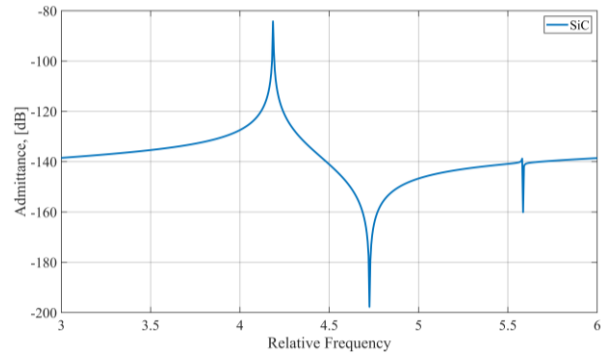


Fig. 6 Input admittance of infinitely long IDT on  $15^\circ$ YX-LN/SiC structure.

Spurious resonances can be seen both in Fig. 5 and Fig. 6. They are due to the secondary Rayleigh SAW mode called the Sezawa mode.

### 3. Conclusion

This paper discussed systematic design of layered structures for wideband and high frequency SAW Resonators.

It was shown that  $k^2$  of 24.0% and  $V_p$  of 3,669 m/s are achievable simultaneously. However, these values are inferior so much to those achievable by the SH0 mode plate mode devices.[5] It may be due to the fact that high velocity substrates behave like the fix boundary for  $15^\circ$ YX-LN plate.

As the next step, the authors are attempting to extend the present discussion to the case when the Bragg reflector is used instead of the high velocity substrates. Sometimes the  $\text{SiO}_2$  layer is inserted between the  $15^\circ$ YX-LN plate and the high-velocity substrate[1],[2]. This configuration can be regarded as a simplified Bragg reflector.

### Acknowledgment

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### 4. References

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